



S/N: 09/546,174
Docket No.: UMC-96-279 CON (JIA-462C1)
Title: HIGH DENSITY PLASMA CHEMICAL
VAPOR DEPOSITION PROCESS
Inv: Chih-Chien Liu et al.
Replacement Sheet

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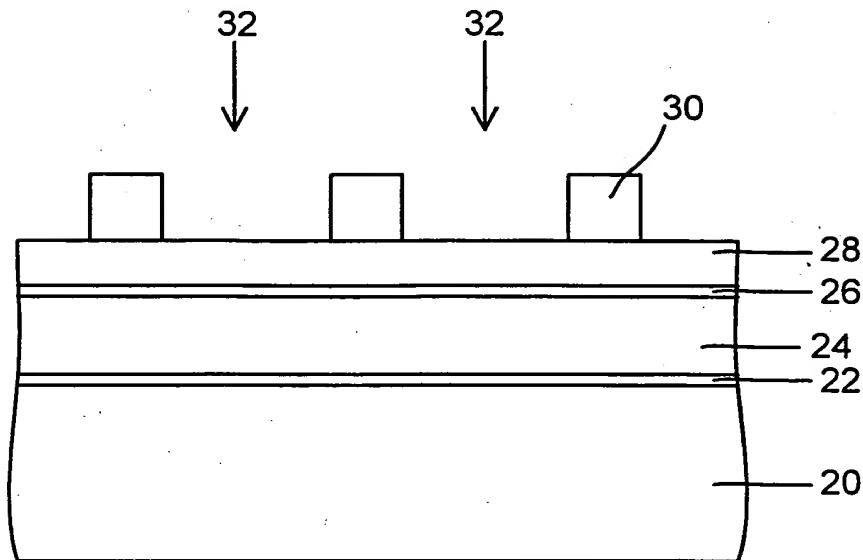


FIG. 1

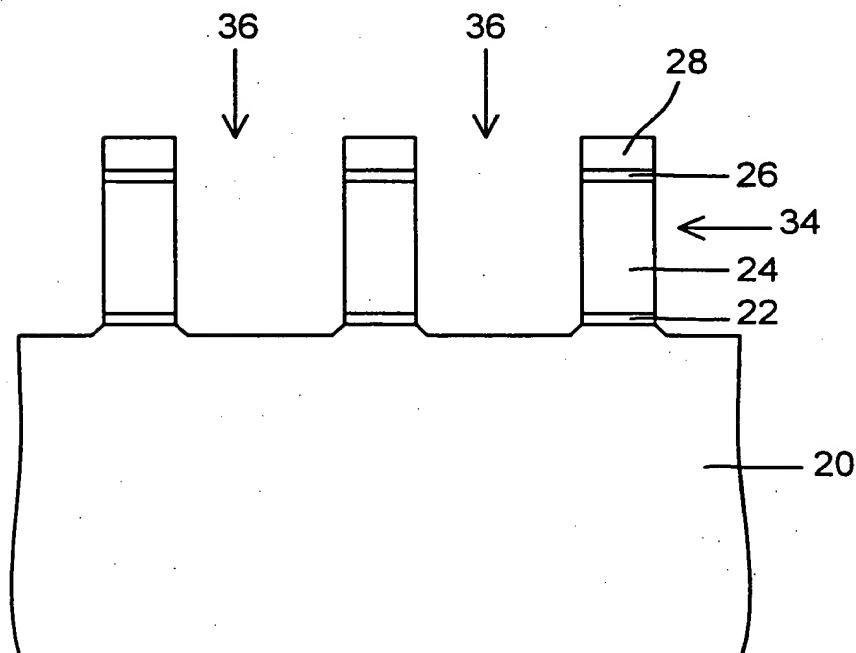


FIG. 2



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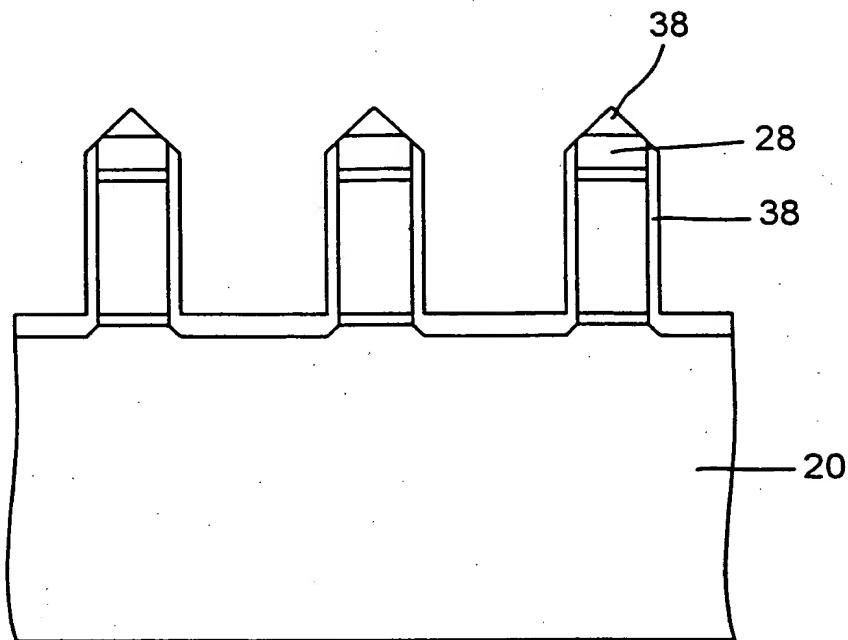


FIG. 3

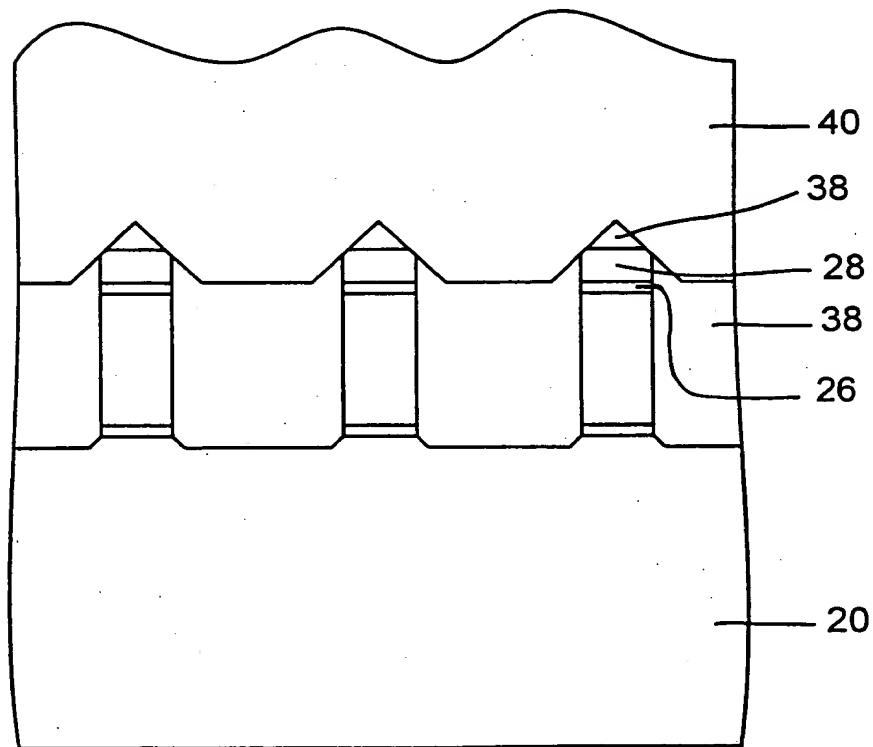


FIG. 4



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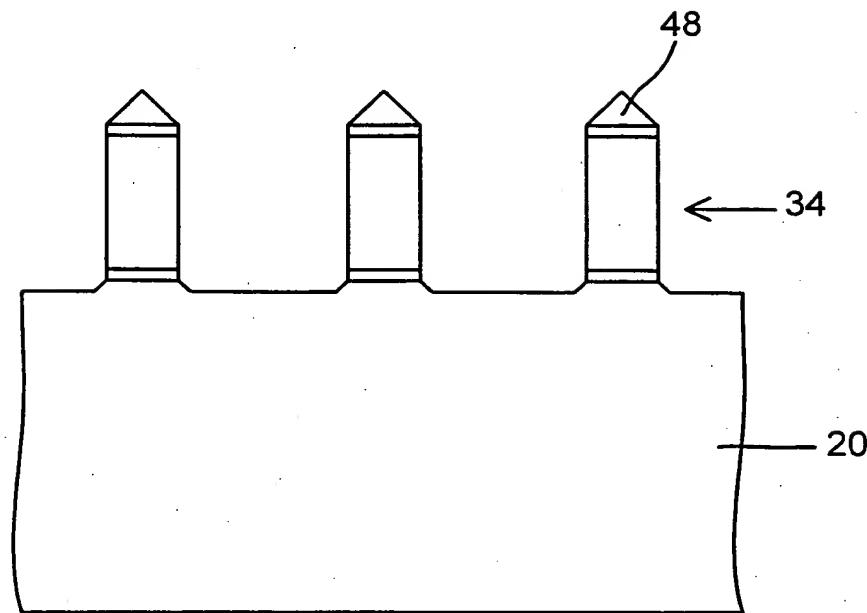


FIG. 5

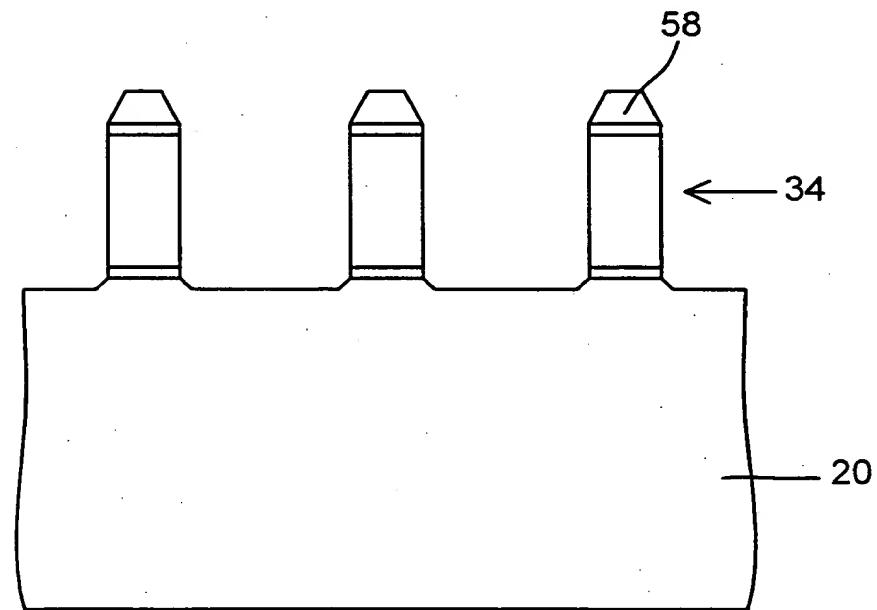


FIG. 6

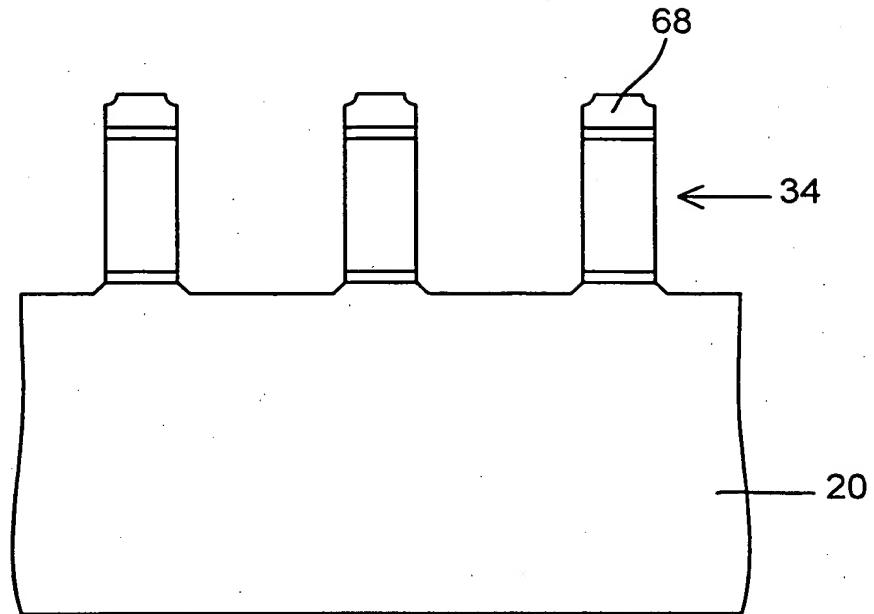


FIG. 7

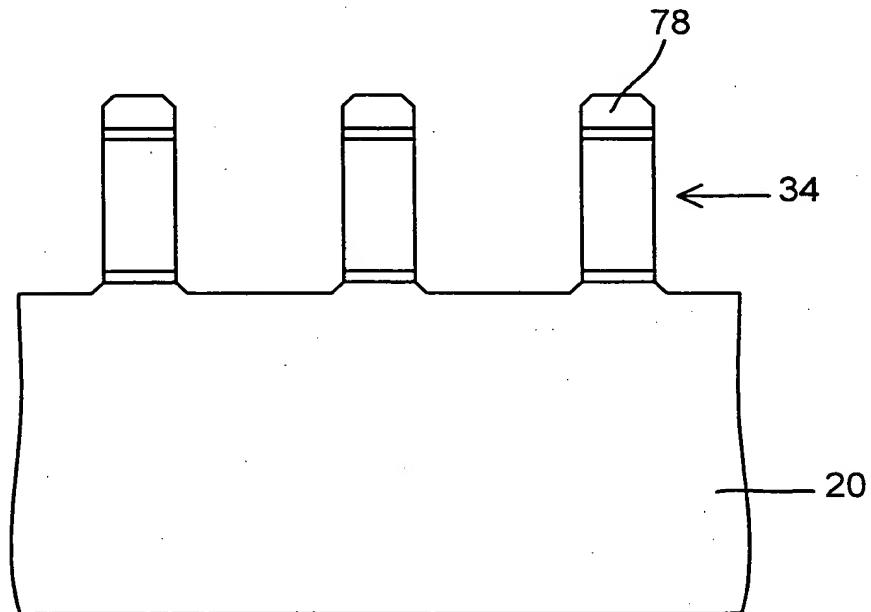


FIG. 8